Research (What is	Monoisotopic Si, Ge and Si <sub>1-x</sub> Ge <sub>x</sub> alloy layers for Si photonics
it about?)	
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We find (The	Epitaxially grown <i>monoisotopic</i> Si, Ge, and Si <sub>1-x</sub> Ge <sub>x</sub> layers of high crystal
result)	quality has been produced
Abstract	Silicon chips are the basis of modern processors. The limiting element for higher
	production of them (silicon electronics) are optical connections. High speed optical
	fibers characterize the ineligible sizes and technology for chips. For higher speed
	the transition to silicon photonics it is necessary. One of the problems to do that is a
	technology for the production of silicon of a specified isotope composition.
	We demonstrate the technology of the growth of Si, Ge, and $Si_{1-x}Ge_x$ layers by
	molecular-beam epitaxy with the use of a sublimation source of monoisotopic <sup>30</sup> Si
	or <sup>26</sup> Si and/or gas sources of monogermane <sup>74</sup> GeH <sub>4</sub> . All of the epitaxial layers are of
	high crystal quality. The secondary-ion mass spectroscopy data and Raman data
	suggest the high isotopic purity (99.9%) and structural perfection of the $3^{30}$ Si, $74^{20}$ L $3^{30}$ Si $74^{20}$ L $13^{30}$ Si $74^{20}$ Si
	Ge, and $SI_{1-x}$ Ge <sub>x</sub> layers. The SI layers doped with Er exhibit an efficient
	photoiuminescence signal.
	The most promising field of application of monoisotopic silicon, germanium, or their allows $\binom{28}{28}$ , $\binom{74}{74}$ , $\binom{30}{28}$ , $\binom{74}{74}$ , is the application of devices for question
	their alloys ( $S_{11-x}$ , $G_{x}$ , $S_{11-x}$ , $G_{x}$ ) is the engineering of devices for quantum
	carculations, specifically, for a quantum computer.

Representative articles 2016-2017, quartiles	<ol> <li>Detochenko A.P., S.A. Denisov, M.N. Drozdov, A.I. Mashin, V.A. Gavva, A.D. Bulanov, A.V. Nezhdanov, A.A. Ezhevskii, M.V. Stepikhova, V.Yu. Chalkov, V.N. Trushin, D.V. Shengurov, V.G. Shengurov, N.V. Abrosimov, H. Riemann. Epitaxially grown monoisotopic Si, Ge, and Si<sub>1-x</sub>Ge<sub>x</sub> alloy layers: production and some properties. Semiconductors. 50(3), 345-348 (2016).</li> </ol>	Q4
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	Q-index (Qi) of the result	-

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0.45-µm-thick Si layer deposited from a monoisotopic <sup>30</sup>Si source onto a Si(100) substrate: the determination of the purity of the layer and the sharpness of the layer–substrate interface.



Internuclear communication in a silicon photonics processor.



Monoisotopic Si<sub>1-x</sub>Ge<sub>x</sub> heterostructure.

